

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Shoriki NARITA et al.

Serial No. 09/988,704

Filed November 20, 2001



: **Confirmation No. 9134**

: Docket No. 2001\_1718A

: Group Art Unit 2625

: Examiner Sheela Chawan

METHOD AND APPARATUS FOR CORRECTING  
INCLINATION OF IC ON  
SEMICONDUCTOR WAFER

**Mail Stop: Amendment**

**PETITION FOR EXTENSION OF TIME**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Petition hereby is made for a one month extension of time to respond to the communication of  
December 29, 2004.

The fee of \$120.00 is

(X) submitted herewith.

() to be charged to Deposit Account No. 23-0975. A duplicate copy of this Petition is  
enclosed.

() Small entity status of this application is established by a Small Entity Status Assertion  
which

() is enclosed.

() has been previously submitted.

Respectfully submitted,

Shoriki NARITA et al.

By

W. Douglas Hahm  
Registration No.44,142  
Attorney for Applicants

05/03/2005 HALI11 00000101 09988704

01 FC:1251

120.00 OP

WDH/ck  
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April 29, 2005